

## Supporting Information

### Stable n-Type Conduction in WO<sub>x</sub>-CNT Hybrid Films

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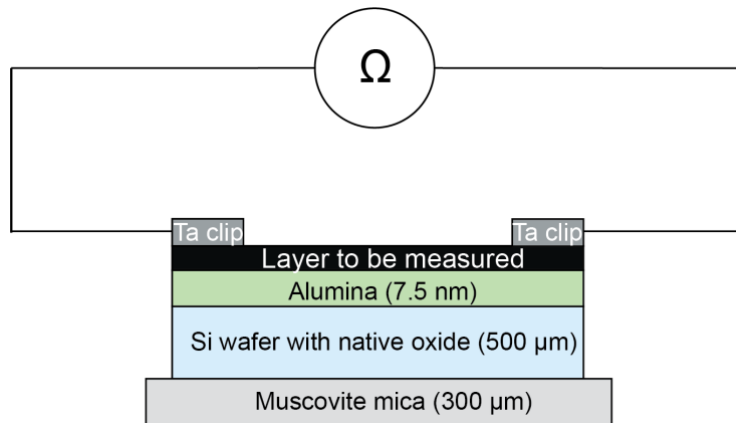
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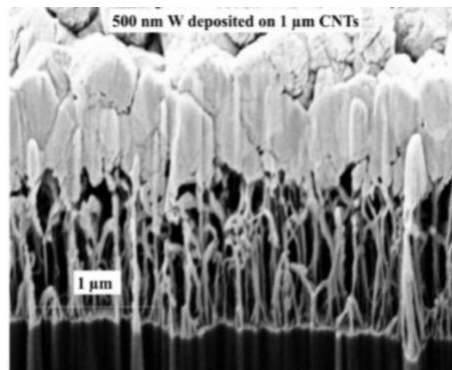
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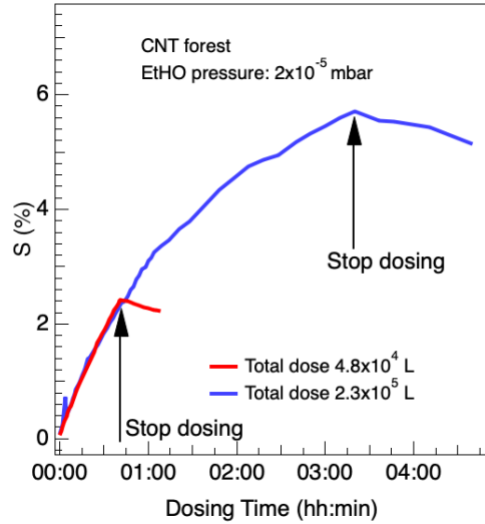
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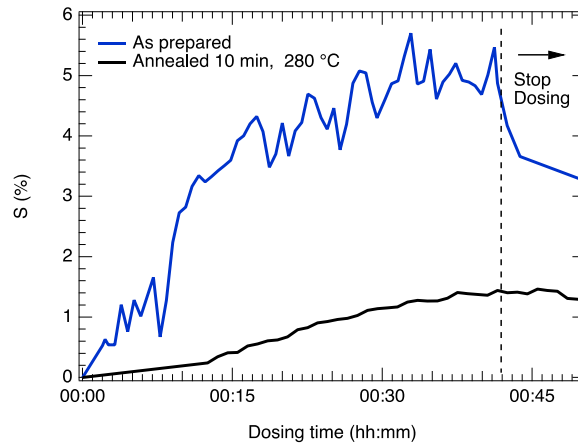
**Figure S1.** Geometry of the resistivity measurements performed under UHV conditions. Layer thicknesses are not drawn to scale. The thickness of the Ta clips was approximately 200  $\mu\text{m}$ .



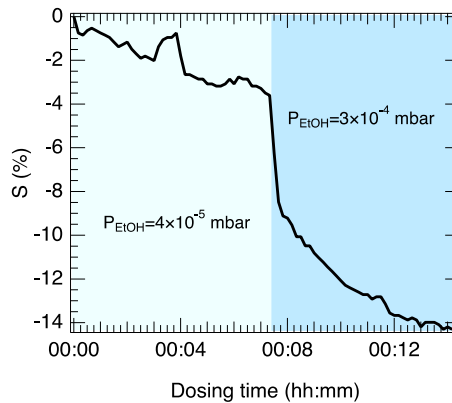
**Figure S2.** SEM image of FIB-cross section of 500 nm  $\text{WO}_x$  layer deposited by DCMS on CNTs forest. (CNTs density:  $7.5 \times 10^3$  CNTs/ $\text{mm}^2$ ).



**Figure S3.** Exposure of a CNTs sample to EtOH in UHV ( $p=2 \times 10^{-5}$  mbar), to verify the reproducibility of the data and find the saturation dose. The total amount of EtOH dosed is reported for each of the two exposures.



**Figure S4.** Sensitivity measurements for the NS- $\text{WO}_x$  deposited on Si wafer during exposure to EtOH in UHV (partial pressure  $p=2 \times 10^{-5}$  mbar) at RT (blue) and after annealing at 280 °C for 10 minutes in UHV (black).



**Figure S5.** Exposure to EtOH of the NS- $\text{WO}_x$ /CNTs hybrid in two different pressure regimes.